<u>Computational Fluid Dynamics analysis of Rectangular</u> <u>Microchannel Heat sink</u>

A Major Thesis Submitted in Partial Fulfillment of the requirements for the award of the degree of

Master of Technology

In

Thermal Engineering



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SESSION 2015-17

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DECLARATION

I hereby declare that the work which being presented in the major thesis entitled "<u>Computational Fluid Dynamics analysis of Rectangular Microchannel Heat sink</u>" in the partial fulfilment for the award of the degree of Master of Technology in "Thermal Engineering" submitted to Delhi Technological University (Formerly Delhi College of Engineering), is an authentic record of my own work carried out under the supervision of Dr. B. B. ARORA, Department of Mechanical Engineering, Delhi Technological University (Formerly Delhi College of Engineering). I have not submitted the matter of this dissertation for the award of any other Degree or Diploma or any other purpose what so ever.

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CERTIFICATE

This is to certify that **SUBODH CHANDRA**, (2K15/THE/15), student of M.Tech, "THERMAL ENGINEERING", Delhi Technological University, has submitted the dissertation titled "<u>Computational Fluid Dynamics analysis of Rectangular</u> <u>Microchannel Heat sink</u>" towards the partial fulfillment of the requirements for the award of the degree of Master of Technology under my guidance and supervision.

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ACKNOWLEDGEMENT

It is said that gratitude is a virtue. This part is dedicated to special thanks that I would like to deliver to the people who helped me in making the fulfilment of this thesis project possible.

I take great pride in expressing my unfeigned appreciation and gratitude to my learned mentor **DR. B. B. ARORA**, and Department of Mechanical Engineering, Delhi Technological University (Formerly Delhi College of Engineering), for their invaluable inspiration, guidance and continuous encouragement throughout this project work. His critics and suggestions on my work have always guided me towards perfection. This work is simply the reflection of his thoughts, ideas, concepts and above all his efforts. Working under his guidance has been a privilege and an excellent learning experience that I will cherish for a long time.

I express my deepest gratitude to PROF. R.S. MISHRA, Head of Department Mechanical Engineering Delhi Technological University (Formerly Delhi College of Engineering). Lastly, I would like to thank my friends Mr. CHINMAY JAIN, Mr. ASHUTOSH MISHRA and Mr. TSEWANG TAMCHOS who helped me a lot.

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Computational Fluid Dynamics analysis of Rectangular Microchannel Heat sink

ABSTRACT

In the study, the analysis of fluid flow and heat transfer in a rectangular microchannel heat sink has been carried out with the help of computational fluid dynamics (CFD). The experimental work done performed by Lee and Mudawar (2002) was simulated for this study. The CFD model equations are solved to analyze the hydrodynamic and thermal behaviour of the rectangular microchannel heat sink. The geometry of the problem is created in Solidworks while meshing has been done in ANSYS Workbench. The model has been solved by ANSYS Fluent 15 solver.

The three-dimensional heat transfer characteristics of the heat sink were analyzed numerically by solving the conjugate heat transfer problem involving simultaneous determination of the temperature distribution in both the solid and liquid regions. The measured pressure drop and temperature distributions show good agreement with the corresponding numerical results. These findings demonstrate that the conventional Navier–Stokes and energy equations can adequately predict the fluid flow and heat transfer characteristics of micro-channel size used in present study.

Key Words: Microchannels, CFD, Fluent, Temperature distribution, pressure drop

CONTENT

DECLARATION	<u> </u>
CERTIFICATE	1
ACKNOWLEDGEMENT	
ABSTRACT	<u> </u>
CONTENT	v
LIST OF FIGURES	VII
LIST OF TABLES	VIII
INTRODUCTION	1
1.1 MICROCHANNEL CONCEPT AND EARLY WORK	3
1.2. FLOW CHANNEL CLASSIFICATION	3
1.3 INTRODUCTION OF COMPUTATIONAL FLUID DYNAMICS (CFD)	5
1.4 AIM OF THE PRESENT WORK	6
1.5 OUTLINE OF THE PROJECT REPORT	7
LITERATURE REVIEW	8
COMPUTATIONAL FLUID DYNAMICS- THEORY AND MODEL EQUATIONS	19
3.1 MATHEMATICAL FORMULATION: GOVERNING EQUATIONS	20
3.1.1 MASS CONSERVATION EQUATION	20
3.1.2 MOMENTUM CONSERVATION EQUATION	20
3.1.3 ENERGY EQUATION	21
3.2 BOUNDARY CONDITIONS	21
3.3 TECHNIQUES FOR NUMERICAL DISCRETIZATION	23
3.3.1 THE FINITE DIFFERENCE METHOD	23

3.3.2 THE FINITE ELEMENT METHOD	23
3.3.3 The Finite volume Method	23
3.3.4 Spectral Methods	23

MICROCHANNEL HEAT SINK-THEORY, MODEL EQUATIONS AND FABRICATION TECHNOLOGY 24

4.1 WHY MICROCHANNEL?	24
4.2 MICROCHANNEL HEAT SINK- MODEL EQUATIONS	25
4.2.1HEAT TRANSFER IN MICROCHANNELS	26
4.3 METALLIC MICROCHANNEL HEAT SINK	28
4.4 FABRICATION OF MICROCHANNELS	28
4.4.1 Photolithography:	28
4.4.2 Anisotropic Wet Etching	29
4.4.3 ANISOTROPIC DRY ETCHING	29
4.4.4 DRIE AND RIE (REACTIVE ION ETCHING):	30
4.4.5 FABRICATION OF MICROCHANNELS IN COPPER	30
4.4.5.1 Laser Micromachining	30
4.4.5.2 Focused Ion Beam Milling	30
4.4.5.3 Micro Electro discharge Machining (Micro EDM)	31
MODELING OF FLUID FLOW IN RECTANGULAR MICROCHANNEL	32
5.1 PROBLEM DESCRIPTION	33
5.2 DETAILED GEOMETRY OF COMPUTATIONAL DOMAIN	34
5.3 Meshing of computational domain	36
5.4 Physical model	37
5.5 MATERIAL PROPERTIES	37
5.6 GOVERNING EQUATIONS	37
5.7 BOUNDARY CONDITIONS	38
5.8 METHOD OF SOLUTION	39
RESULTS AND DISCUSSIONS	40
CONCLUSIONS	55

REFERENCES	56

List of figures

Fig.3.1 Various Boundary conditions22
Fig. 4.1 Schematic representation of Microchannel heat sink25
Figure 5.1 Experimental arrangements for testing of micro channel32
Figure 5.2 (a) Test module (b) Microchannel heat sink33
Figure 5.3 a) unit cell b) computational domain35
Figure 5.4 Isometric view of computational domain in Ansys35
Figure 5.5 Isometric view of mesh structure in computational domain36
*Figure 6.1 Temperature distribution at bottom wall of Heat sink at qeff =100 W/cm2
and Re of 89043
*Figure 6.2 Temperature distribution at Top wall of Heat sink at qeff =100 W/cm2 and
Re of 89043
*Figure 6.3 Temperature distribution at Channel bottom wall of Heat sink at qeff =100
W/cm2 and Re of 89044
*Figure 6.4 Temperature distribution at Channel side wall of Heat sink at qeff =100
W/cm2 and Re of 89044
Figure 6.5Velocity contours in complete fluid domain at qeff =100 W/cm2 and Re of 890
45
Figure 6.6 Velocity contours nearer to inlet at qeff =100 W/cm2 and Re of 89045
Figure 6.7 Velocity contours nearer to outlet at qeff =100 W/cm2 and Re of 89046
Figure 6.8 Pressure contours nearer to inlet at $qeff = 100 \text{ W/cm2}$ and Re of 890 46
Figure 6.9 Pressure contours nearer to outlet at qeff =100 W/cm2 and Re of 89047
Figure 6.10Temperature contours of complete heat sink at symmetry plane at qeff =100
W/cm2 and Re of 89047
*Figure 6.11 Temperature distributions at bottom wall of Heat sink at qeff =200 W/cm2
and Re of 86448
*Figure 6.12 Temperature distributions at top wall of Heat sink at qeff =200 W/cm2 and
Re of 86448
*Figure 6.14 Temperature distribution at Channel side wall of Heat sink at qeff =200
W/cm2 and Re of 86449
*Figure 6.13 Temperature distribution at Channel bottom wall of Heat sink at qeff =200
W/cm2 and Re of 86449
Figure 6.15 Velocity contours in entire fluid domain at qeff =200 W/cm2 and Re of 864
50 Figure 6.16 Velocity contours nearer to inlet at qeff =200 W/cm2 and Re of 86450

Figure 6.17Velocity contours nearer to inlet at qeff =200 W/cm2 and Re of 8645	51
Figure 6.18 Pressure contours nearer to inlet at qeff =200 W/cm2 and Re of 8645	51
Figure 6.19Pressure contours nearer to inlet at qeff =200 W/cm2 and Re of 8645	52
Figure 6.20 Temperature contours of complete heat sink at symmetry plane at qeff $=20$)0
W/cm2 and Re of 864	52
Figure 6.21Graph between Pressure drop and Reynolds Number5	53
Figure 6.22 energy balance predictions for water temperature rise from heat sink inlet	to
outlet: (a) qeff= 100 W/cm2, (b) q eff = 200 W/cm25	53
Figure 6.23Graph between friction factor and Reynolds Number5	54

List of tables

Table 1.1	
Table 1.2	
Table 4.1 Nusselt No. For Various Geometries	
Table 5.1 Dimensions of unit cell micro channel	
Table 5.2 Dimensions of computational domain	
Table 5.3 Material Properties	
Table 5.4. Zonewise Boundary Condition	
Table 5.5 Relaxation factor	

CHAPTER-1

INTRODUCTION

Heat is an unavoidable by product of any electronic device or mechanical heat engine. The aim of every thermal engineer is to minimize this heat or remove this heat from its source. The efficientremoval ofthis heat is referred as thermal management. This heat sink is the device which is used for sinking away the heat dissipated in the engine or any other device. In case of high heat flux generating electronics device, the miniaturize sizes of these heat generating devices and the strict operatingconditionscreates achallenging situation of efficiently remove the heat produced. The rapid increase in IC speeds, functionality and miniaturization of devices has fueled an extraordinary acceleration in chip heat dissipation and consequently thermal management is becoming a critical bottleneck to system performance.

The Increase in the temperature of semiconductor devices leads to change in various device parameters. For example, in case of Laser diodes, the threshold current (current at which lasing action starts) of the device increases exponentially with the rise in its junction temperature while the slope efficiency of device decreases exponentially with temperature. Apart from this, the reliability of a laser diode is strongly affected by the temperature rise in the active region as the operating lifetime of the device decreases exponentially with temperature. The failure rate of a semiconductor device follows the Arrhenius equation[1]:

$$F=A(e^{-Ea/kT})$$
 1.1

F: Failure rate

- A: Arrhenius constant
- T: Junction Temperature (K)

Ea: Activation energy (eV)

K: Boltzmann's constant $(8.63 \times 10^{-5} \text{ eV/K})$

The failure rate of a component almost doubles with an increase of 10° C (for an Ea of 0.65 eV).

To efficiently remove the heat dissipated from semiconductor devices, micro-machining technology is the current trend which is gaining popularity for the development of highly efficient cooling systems for semiconductor devices. Microchannel cooling is a technology dealing with very small fins that are placed extremely close to the heat dissipating element. Microchannel heat sink is a device which has the ability to remove very high heat flux with minimum temperature rise.

The need for miniaturized scale channels emerges from the way that for a constant temperature difference the heat exchange rate is proportional to the result of the overall heat transfer coefficient U and the heat exchange region A. The higher increment in UA can be accomplished by expanding the overall heat transfer coefficient U which can be raised by expanding the film heat transfer coefficient h. For flow through pipes and tubes, huge increment in h can be accomplished by reducing hydraulic diameter. That is the reason; microchannel heat sinks can disseminate a lot of heat with least rise intemperature. The small size of microchannel heatsink additionally makes them perfectly suited for cooling the space obliged electronic gadgets.

The two essential targets in semiconductor chip thermal management are the lessening of the gadget most extreme temperature and the minimization of thermal resistance of the packaged device. Microchannel heat sinks can efficiently accomplish these goals.

In literature, it is mentioned that microchannelheat sinks can remove heat flux of the order of 1000 W/cm2 with most extreme surface temperatures of under 120° C [2]. The likelihood of accomplishing this level of heat flux removal has brought about various reviews for using microchannel flow for the thermal management of high heat flux

generating electronics frameworks. Many of these examinations concentrated on knowingthe essentials of fluid flow inside a microchannel. Some examination was centered around looking into the flow and heat transfer attributes in microchannels and in customary channels. Hypothetical examination prompting improvement of microchannel heat sinks were done; so additionally were test examinations to acquire new connections and to augment the scope of use of conventional channel relationships to incorporate in case of microchannels.

The investigation of heat transfers andmovement of fluid these channels, which are two basic area of interest, have pulled in more considerations with wide applications in many applications. Microchannel heat sinks are characterized into two types. First is single-phase in which; fluid does not change its phase. In second type; which is known as two phase microchannel heat sink, fluid gets vaporized (due to low fluid velocity and high heat flux).

1.1 Microchannel concept and early work

The goal of every thermal designer is to get the cooling fluid as close as possible to the heat source. To achieve this, liquid flow through microchannels was firstly shown as an effective method for dispersing heat from silicon incorporated device by Tuckerman and Pease (1981) [3]. The original thought prompted various imaginative plans and generated various research activities in the field of microchannel cooling. This exhibition included the testing of an extremely narrow water-cooled heatsink. Minute channels of 50 µm width and 300 µm of depth carved on silicon, and demineralized water was pumped inside these narrow passages as the coolant. It could expel heat flux of 790 W/cm2 and a comparing substrate temperature increase of 71°C above the inlet water temperature. Before continuing with microchannel heat exchange and fluid flow behaviour, it is suitable to present a definition for the expression "microchannel".

1.2. Flow channel classification

Hydraulic diameter can serve the basis of defining microchannel in case of channel is not circular.Mehendale et al. (2000) [4] gave the following basis for the definition of microchannel on the basis of least channel dimension "D" as shown in table 1.1.

Table 1.1

$1\mu m \ \langle \ D \ \langle \ 100 \mu m angle$:	Microchannels
$100\mu m \langle D \langle 1 mm$:	Minichannels
$1 mm \langle D \langle 6 mm$:	Compact Passages
$6 mm \langle D$:	Conventional Passages

Kandlikar (2003) [5] adopted a different classification which has the same basis for its classification i.e. lowest channel dimension "D". It is given in table 1.2.

Table 1.2

$1\mu m \langle D \langle 10\mu m$:	Transitional Microchannels
$10\mu m$ \langle D \langle $200\mu m$:	Microchannels
200 μm $\langle D \langle 3 mm$:	Minichannels
$3 mm \langle D$:	Conventional Passages

A more straightforward arrangement was proposed by Obot (2003) [6] in view of the hydraulic diameter.Obot arranged channels of hydraulic diameter less than 1 mm (D $_{\rm h}$ < 1 mm) as microchannels, which is likewise received by numerous different scientists, for example, Bahrami and Jovanovich (2006) [7] and Bayraktar and Pidugu (2006) [8].This classification is supposed to be most suitable for the reasons for this proposition.

Microchannel heat sinks work on the technologywhich is capable of transferringhigh amount of heat flux which is generated inside small area of semiconductor device during its operation. This heat sinksare normally fabricated by using copper in case of metallic microchannel heat sink which has high thermalconductivity among metals. Few experiments were also carried out using CVD (chemically vapour deposited) diamond as microchannel heat sink material. Siliconis material which is preferred while microchannel heat sink to be produced from semiconductor material itself. The microchannels are fabricated by either micro machining technology in case of metals or well established semiconductor fabrication technology when silicon is used as material for microchannel. A large number of parallel channels in micron range constitute a microchannel heat sink. The shapes are generally circular or rectangular. The coolant which is normally deionised water or water with nanoparticles; is forcefully passed inside these channels to remove heat from heat dissipating device.

Microchannel heat sinks have very high surface area to volume ratio and large convective heat transfer coefficient (comparable to boiling in some cases). Additionally, they posses low mass, small volume and small cooling fluid requirement. These properties makethemagoodchoice for thermal managementof semiconductor devices such as semiconductor laser arrays, highspeedmicroprocessors etc.

1.3 INTRODUCTION OF COMPUTATIONAL FLUID DYNAMICS (CFD)

It will be very expansive and time consuming process if all the work on microchannel heat sink is done practically. To diminish the quantity of trials that should be performed, analysts utilize Computational Fluid Dynamics (CFD) as an instrument for heat exchange investigation. CFD can be utilized as a part of parallel with trial setups with an end goal to anticipate the stream and heat exchange qualities of given surface under the predetermined control parameters. Computational techniques can abbreviate the outline cycle and in this way diminish exploratory expenses. Numerical strategies are widely used to break down the liquid conduct, execution and to plan the microchannels warm sink.

Computational Fluid Dynamics (CFD) is software which is aset of numerical algorithms thatis used to analyze the fluid flow and heat exchange. Arrangements of mathematical model conditions are first created taking after conservation laws. These conditions are then explained utilizing software so as to get the flow parameters all through the computational area. Validation of CFD results is necessary to evaluate the precision of the CFD analysis. The validation is accomplished by contrasting CFD comes about and accessible exploratory, hypothetical, or explanatory information. Validated models end up plainly settled as dependable, while those which come up short the approval test should be adjusted and revalidated. Additionally, demonstrate conditions can be simulated by CFD technique for the design and development of microchannel heat sink.

1.4 AIM OF THE PRESENT WORK

The investigation of fluid flow and heat exchange analysisin microchannels is essential for the innovation purpose and to optimize its geometry and flow parameters. The advancements are taking after the pattern of scaling down in all fields. The researches demonstrate that the microchannels and micro fluidics are considered widely for high heat flux applications. However, there is constrained research identified with the execution investigation of micro fluidicdevices by utilizing CFD. Taking after from the experimental examination of Lee and Mudawar (2002), this study concentrates on the outcome of CFD analysis of microchannel fluid flow and heat exchange, in a rectangular microchannel heat sink.

The aim of present work is

- Computational Fluid Dynamics analysis of rectangular microchannel heat sink to comprehend its hydrodynamic and thermal nature.
- Validation of the CFD models by contrasting the present results with the experimental work of Lee and Mudawar (2002).

1.5 OUTLINE OF THE PROJECT REPORT

Chapter 1: Detailed introduction of project work with focus on importance of thermal management in semiconductor technology, classification of micro channel, its importance in high heat flux cooling and use of CFD in microchannel heat sink analysis.

Chapter 2: Covers detailed literature review on experimental and theoretical analysis of the microchannel heat sink.

Chapter 3: Explains theory and modeling equation of CFD analysis.

Chapter 4:Describes theory and modeling equation of micro channel heat sink. The fabrication technology of microchannel heat sink is also described in this section briefly.

Chapter 5: Describes modeling of Rectangular microchannel heat sink in detail. The various parts in simulation like geometry, meshing, boundary conditions, Temperature and Pressure variation inside microchannel are described in this section.

Chapter 6: Results and discussions

Chapter 7: Conclusion

CHAPTER-2

LITERATURE REVIEW

A lot of experimental and theoretical work on microchannel heat sink has been done in the last decades. Both the industrial and academic people have taken interest in this area. Thefollowing is a review of the research that has been completed on microchannel heat sink. The literature survey is arranged according to similarity to the work done in this thesis. In this literature review emphasis is directed on:

(a). Experimental study of fluid flow and heat transfer in micro channels

(b). Numerical study of fluid flow and heat transfer in micro channels

2.1 EXPERIMENTAL STUDY OF FLUID FLOW AND HEAT TRANSFER INMICRO CHANNELS

With the development of micro fabrication technology, microfluidic systems have beenincreasingly used in different scientific disciplines such as biotechnology, physical andchemical sciences, electronic technologies, sensing technologies etc. Microchannels are oneof the essential geometry for microfluidic systems; therefore, the importance of convectivetransport phenomena in microchannels and microchannel structures has increaseddramatically. In recent years, a number of researchers have reported the heat transfer andpressure drop data for laminar and turbulent liquid or gas flow in microchannels.

The conceptof micro channel heat sink at first proposed by **Tuckermann and Pease** (1981) [3], theydemonstrated that the micro channel heat sinks, consisting of micro rectangular flowpassages, have a higher heat transfer coefficient in laminar flow regime than that in turbulentflow through conventionally-sized devices. They said that the heat transfer can be enhanced by reducing the channel height down to micro scale. This pioneering work initiated otherstudies, some confirmed findings reported by others. Many researchers compared theirnumerical or analytical studies with Tuckerman and Pease.

Wang and Peng (1995) [9] had investigated experimentally the single-phase forced convectiveheat transfer characteristics of water/methanol flowing through micro-channels withrectangular cross section of five different combinations, maximum and minimum channelsize varying from $(0.6 \times 0.7 \text{ mm}^2)$ to $(0.2 \times 0.7 \text{ mm}^2)$. The results provide significant dataand considerable insight into the behavior of the forced-flow convection in micro-channels.

Peng and Peterson (1996) [10]had also investigated experimentally the single-phase forcedconvective heat transfer micro channel structures with small rectangular channels havinghydraulic diameters of 0.133–0.367 mm and distinct geometric configurations. The results indicate that geometric configuration had a significant effect on single-phase convective heattransfer and flow characteristics. The laminar heat transfer found to be dependent upon the spect ratio i.e. the ratio of hydraulic diameter to the centre to centre distance of microchannels. The turbulent flow resistance was usually smaller than predicted by classical relationships.

Fedorov and Viskanta (2000)[11] developed a three dimensional model to investigate the conjugate heat transfer in a micro channel heat sink with the same channel geometry used in the experimental work done by Kawano et al (1998) [12]. This investigation indicated that the average channel wall temperature along the flow direction was nearly uniform except in the region close to the channel inlet, where very large temperature gradients were observed. This allowed them to conclude that the thermo–properties are temperature dependent. The modifications of thermo-physical properties in the numerical process are very difficult astemperature and velocity are highly coupled.

Jiang et al. (2001) [13]performed an experimental comparison of microchannel heat exchanger with microchannel and porous media. The effect of the dimensions on heat transfer wasanalyzed numerically. It was emphasized that the heat transfer performance of themicrochannel heat exchanger using porous media is better than using of microchannels, butthe pressure drop of the former is much larger.

Qu and Mudawar (2002) [14]have performed experimental and numerical investigations of pressure drop and heat transfer characteristics of single-phase laminar flow in 231 μ m by713 μ m channels. Deionized water was employed as the cooling liquid

and two heat fluxlevels, 100 W/cm2 and 200 W/cm2, defined relative to the planform area of the heat sink, were tested. Good agreement was found between the measurements and numerical predictions, validating the use of conventional Navier–Stokes equations for micro channels. For the channel bottom wall, much higher heat flux and Nusselt number values are encountered near the channel inlet.

Qu and Mudawar (2004) [15]conducted a three-dimensional fluid flow and heat transferanalysis for a rectangular micro channel heat sink using a numerical method similar to thatproposed by both Kawano et al. (1998), and Fedorov and Viskanta. (2000) This modelconsidered the hydrodynamic and thermal developing flow along the channel and found thatthe Reynolds number would influence the length of the developing flow region. It was alsofound that the highest temperature is typically encountered at the heated base surface of theheat sink immediately adjacent to the channel outlet and that the temperature rise along theflow direction in the solid and fluid regions can both be approximated as linear.

Mishan et al. (2007) [16]has worked on heat transfer and fluid flow characteristic of arectangular microchannel experimentally, having water as a working fluid. The experimentalresults of pressure drop and heat transfer confirm that including the entrance effects, theconventional theory is applicable for water flow through microchannels. They havedeveloped new method for measurement of fluid temperature distribution and it gives thefluid temperature distribution inside the channel.

Lee and Mudawar (2007) [17]]have done experimental work to explore the microchannelcooling benefits of water-based nanofluids containing small concentrations of Al2O3. It wasobserved that the presence of nanoparticles enhances the single-phase heat transfercoefficient, especially for laminar flow. Higher heat transfer coefficients were achievedmostly in the entrance region of micro-channels. However, the enhancement was weaker in the fully developed region. Higher concentrations also produced greater sensitivity to heatflux. A large axial temperature rise was associated with the decreased specific heat for thenanofluid compared to the base fluid. For two-phase cooling, nanoparticles causedcatastrophic failure by depositing into large clusters near the channel exit due to localizedevaporation once boiling commenced. **Chein and Chuang (2007)** [18] have addressed microchannel heat sink (MCHS) performanceusing nanofluids as coolants. They have carried out a simple theoretical analysis that indicated more energy and lower microchannel wall temperature could be obtained under the assumption that heat transfer could be enhanced by the presence of nanoparticles. The theoretical results were verified by their own experimental results. It was observed that nanofluid-cooled MCHS could absorb more energy than water-cooled MCHS when the flow rate was low. For high flow rates, the heat transfer was dominated by the volume flow rate and nanoparticles did not contribute to the extra heat absorption.

Jung et al (2009) [19]have studied experimentally the heat transfer coefficients and frictionfactor of Al2O3 with diameter of 170 nm in a rectangular micro channel. Appreciableenhancement of the convective heat transfer coefficient of the nanofluids with the base fluidof water and a mixture of water and ethylene glycol at the volume fraction of 1.8 volumepercent was obtained without major friction loss. It has been found that the Nusselt numberincreases with increasing the Reynolds number in laminar flow regime, which iscontradictory to the result from the conventional analysis.

Ergu et al. (2009) [20]had described the pressure drop and local mass transfer in a rectangularmicrochannel having a width of 3.70 mm, height of 0.107 mm and length of 35 mm. Thepressure drop measurements were carried out with distilled water as working fluid atReynolds numbers in the range of 100–845, while mass transfer measurements with achemical solution at Reynolds numbers in the range of 18–552 by using the electrochemicallimiting diffusion current technique (ELDCT). Experimental friction factors were foundslightly higher than those calculated by theoretical correlation. The Sherwood numbercorrelation was also obtained.

2.2 NUMERICAL STUDY OF FLUID FLOW AND HEAT TRANSFER IN MICRO CHANNELS

To design an effective microchannel heat sink, fundamental understanding of thecharacteristics of the heat transfer and fluid flow in microchannel are necessary. At the earlystages the designs and relations of macroscale fluid flow and heat transfer were employed. The strength of numerical simulations is the possibility to investigate small details that are impossible to observe in experiments.

Liu and Garimella (2004) [21]have studied numerically on fluid flow and heat transfer in microchannels and confirmed that the behavior of micro channels is quite similar to that of conventional channels. And their analysis showed that conventional correlations offer reliable predictions for the laminar flow characteristics in rectangular micro channels over a hydraulic in the range of 244–974 μm .

A numerical study has been performed by Li et al. (2004) [22]on the same micro channel heatsink developed by Qu and Mudawar (2000)in order to explore the impact of geometric andthermo- physical parameters of the fluid on its flow behavior and heat transfer characteristics.

The authors have acknowledged the scattered results obtained in past micro fluidics studies from various authors, and pointed out the strong differences of empirical correlations derived therein. These differences are especially true when comparing works that studied singlemicro channels to those who considered entire micro channel heat sinks. Thus, the authorsnoted a need to develop numerical models that provide more insight into the fundamental physics of the transport processes involved.

Roy et al. (2004) [23]has studied a steady, laminar flow and heat transfer of a nanofluid flowinginside a radial channel between two coaxial and parallel discs. The nondimensionalgoverning equations of mass, momentum and energy were solved by computational fluiddynamics method. Results presented in this paper are for a water/aluminium oxide particlenanofluid (H2O– γ Al2O3). Results have shown that the inclusion of nanoparticles in atraditional coolant can provide considerable improvement in heat transfer rates, even at smallparticle volume fractions. Increases in the resulting wall shear stresses were also noticed.

Gamrat et al. (2005) [24] analyzed three-dimensional flow and associated heat transfer in arectangular micro channel heat sink numerically. The numerical simulation considered thecoupling between convection in micro channels and conduction in the walls and in thecomplete solid material. The results of numerical simulations using the continuum model(conventional mass, Navier–Stokes and energy equations) were in good agreement withpublished data on flow and heat transfer in three dimensional channels.

Hetsroni et al. (2005) [25]has verified the capacity of conventional theory to predict thehydrodynamic characteristics of laminar Newtonian incompressible flows in micro channels in the range of hydraulic diameter from = 15 h D to $D m h = 4010 \mu$. They have compared their results with the data available in open literature. The theoretical models were subdivided in two groups depending on the degree of correctness of the assumptions. The first group includes the simplest one-dimensional models assuming uniform heat flux, constant heattransfer coefficient, etc. The comparison of these models with experiment shows significant discrepancy between the measurements and the theoretical predictions The second group is based on numerical solution of full Navier–Stokes and energy equations, which account thereal geometry of the micro-channel, presence of axial conduction in the fluid and wall, energy dissipation, non adiabatic thermal boundary condition at the inlet and outlet of the heat sink, dependence of physical properties of fluid on temperature, etc. These models demonstrate afairly well correlation with the available experimental data.

Khanafer et al. (2003) [26]has investigated heat transfer enhancement in a twodimensionalrectangular enclosure utilizing nanofluids. The material used is water/cupper. The developedtransport equations were solved numerically using the finite-volume approach along with thealternating direct implicit procedure. The effect of suspended ultrafine metallic nanoparticleson the fluid flow and heat transfer processes within the enclosure was analyzed. The heattransfer correlation of the average Nusselt number for various Grashof numbers and volumefractions was also presented.

Jou and Tzeng (2006) [27]have used the Khanafer's model to analyze heat transfer performanceof nanofluids inside an enclosure taking into account the solid particle dispersion. Transportequations were modeled by a stream function-vorticity formulation and solved numericallyby finite difference approach. Based upon the numerical predictions, the effects of Rayleighnumber (Ra) and aspect ratio on the flow pattern and energy transport within the thermalboundary layer were presented. It was observed that increasing the buoyancy parameter andvolume fraction of nanofluids cause an increase in

the average heat transfer coefficient. Finally, the empirical equation was built between average Nusselt number and volumefraction.

Li and Peterson (2007) [28]have worked on identification of the possible mechanisms that contribute to the enhanced effective thermal conductivity of nanoparticle suspensions(nanofluids). The mixing effect of the base fluid in the immediate vicinity of thenanoparticles caused by the Brownian motion was analyzed, modeled and compared with existing experimental data available in the literature. The simulation results using CFX 5.5.1software indicate that this mixing effect can have a significant influence on the effective thermal conductivity of nanofluids. They have found pressure, velocity and temperature profile around the nanoparticles.

A developing laminar forced convection flow of a water–Al2O3 nanofluid in a circular tube, submitted to a constant and uniform heat flux at the wall, has been numerically investigated Bianco et al. (2009). CFD method was used to simulate the model equations. A singleand two-phase model (discrete particles model) was employed with either constant or temperature dependent properties. The maximum difference in the average heat transfercoefficient between single- and two-phase models results was found about 11%. Convective heat transfer coefficient for nanofluids was found as greater than that of the base liquid. Heattransfer enhancement increases with the particle volume concentration, but it is accompanied by increasing wall shear stress values. Higher heat transfer coefficients and lower shearstresses were detected in the case of temperature dependents models. The heat transfer alwaysimproves, as Reynolds number increases.

Xu et al. (2008) [29]considered liquid flow in 30–344 μ m(hydraulic diameter) channels atReynolds numbers varies from 20 to 4000. Their results showed that characteristics of flow inmicro channels agree well with conventional behavior predicted by Navier–Stokes equations. They have suggested that deviations from classical behavior reported in earlier studies mayhave resulted from errors in the measurement of micro channel dimensions, rather than anymicro scale effects.

Sabbah et al. (2008) [30] observed that the prediction of heat transfer in micro-channels becomes difficult with increase in complicacy of the geometry of the micro-channels, requiring three dimensional analysis of heat transfer in both solid and liquid phases.

Computational FluidDynamics (CFD) models were implemented in order to study and optimize the thermal andhydraulic performance of micro channel heat sinks. Despite the small width of the channels,the conventional Navier Stokes and energy conservation equations still apply to the MCHE flow due to the continuum of the working fluid where the channel width is many times largerthan the mean free path of liquid molecules (water). The microchannel is characterized by thelaminar flow in it, due to the small hydraulic diameter of the channel which results in lowReynolds numbers

Oztop et al. (2008) [31]has carried out CFD study on heat transfer and fluid flow due tobuoyancy forces in a partially heated rectangular enclosure filled with nanofluids. Thetemperature of the right vertical wall kept lower than that right wall while other two walls are insulated. The finite volume technique is used to solve the governing equations. Differenttypes of nanoparticles were tested. An increase in mean Nusselt number was found with the volume fraction of nanoparticles for the whole range of Rayleigh number. Heat transfer also increases with increasing of height of heater. It was also found that the heater location affects the flow and temperature fields when using nanofluids.

Mokrani et al. (2009) [32] developed a reliable experimental device and adequate methodologyto characterize the flow and convective heat transfer in flat micro channels. The study wasconcerned with measurement of pressure drop and heat transfer by a Newtonian fluid flowinside a flat micro channel of rectangular cross-section whose aspect ratio is sufficiently highthat the flow can be considered two dimensional They considered the hydraulic diameter astwice of the channel height. The mathematical model used to describe the convective heattransfer between the walls and the fluid takes into account the whole field (solid wall andfluid layer) and the coupling between the conduction and the convection modes. Finally, theyconcluded that the conventional laws and correlations describing the flow and convectiveheat transfer in ducts of large dimension are directly applicable to the micro channels ofheights between 500 and 50 microns

Muthtamilselvan et al. (2009) [33] has conducted a numerical study to investigate the transportmechanism of mixed convection in a lid-driven enclosure filled with nanofluids. The twovertical walls of the enclosure were kept insulated while the horizontal walls

were at constant speed. The model equations were discretized by finite volume technique with a staggered grid arrangement. The SIMPLE algorithm is used for handling the pressure velocity coupling. Numerical solutions areobtained for a wide range of parameters and copper-water nanofluid was used with Pr = 6.2. The streamlines, isotherm plots and the variation of the average Nusselt number at the hotwall have been presented and discussed. The variation of the average Nusselt number wasobserved linear with solid volume fraction.

In one of the recent studies by **Al-Nmir et al.** (2009) [34], an investigation of the hydrodynamicand thermal behavior of the flow in parallel plate micro heat exchanger was performed numerically, by adopting a combination of both the continuum approach and the possibility of slip at the boundaries. In their work, both viscous dissipation and internal heat generationwere neglected. Fluent analysis was made based on solving continuum and slip boundarycondition equations. Effects of different parameters; such as, Knudsen number (Kn), heatcapacity ratio (Cr), effectiveness (ε), and number of transfer units (NTU) were examined. The study showed that both the velocity slip and the temperature jump at the walls increase withincreasing Kn. The increase of the slip conditions reduces the frictional resistance of the wallagainst the flow, and under the same pressure gradient, pumping force leads to that the fluidflows much more in the heat exchanger.

Very recently, **Mathew and Hegab** (2009) [35]theoretically analyzed the thermal performance of parallel flow micro heat exchanger subjected to constant external heat transfer. The model equations predict temperature distributions as well as effectiveness of the heat exchanger. Moreover, the model can be used when the individual fluids are subjected to either equal or unequal amounts of external heat transfer.

One of the comprehensive studies in counter flow micro channel heat exchanger area wasdone by Hasan et al. 2009. In this work, numerical simulations were made to study the effectof the size and shape of channels; such as circular, square, rectangular, iso-triangular, andtrapezoidal, in counter flow exchanger. The results show that for the same volume of heatexchanger, increasing the number of channels leads to an increase in both

effectiveness and pressure drop. Also circular channels give the best overall performance (thermal and hydraulic) among various channel shapes.

Kang and Tseng (2007) [36]theoretically modeled thermal and fluidic characteristics of a crossflowmicro heat exchanger assuming that flows in rectangular channels, where fin height andwidth are 32 μ m and 200 μ m respectively, are incompressible, steady, and laminar. Thesimulated results were validated with the experimental data. The effects of change of materialfrom cupper to silicon and dimensions on its performance were investigated. The study showsthat under the same effectiveness value, a small rise in the temperatures of working fluidsresults in an increase of the heat transfer rate, but a decrease in pressure drop occurs.

Foli et al. (2006) introduced multi-objective genetic algorithms for determining the optimalgeometric parameters of the microchannels heat exchanger to maximize the heat transfer rateunder specified design constraints. CFD analysis with an analytical method of calculating theoptimal geometric parameters was also performed. This paper is important and a good work, because there is limited published literature on attempts at designing the exchanger foroptimal performance.

Tsuzuki et al. (2009) [37]proposed a new flow configuration, named S-shaped fin configuration reduce the micro channel heat exchanger pressure drop. A numerical study using a 3DCFD code, FLUENT, was performed to find Nusselt number correlations for the exchanger.

The copper heat exchanger, whose dimensions are $1240 \times 68 \times 4.75 \text{ mm3}$, comprises coldwater channels and hot CO2 channels. For both hot and cold sides, simulations were done toattain accurate empirical correlations for different temperatures.

Rebrov et al. (2011) [38]has reviewed the experimental and numerical results on fluid flowdistribution, heat transfer and combination thereof, available in the open literature. They havefound that the experiments with single channels are in good agreement with predictions using the published correlations. The accuracy of multichannel experiments is lower due to flowmaldistribution. Special attention was devoted to theoretical and experimental studies on the effect of a flow maldistribution on the thermal micro reactors.

The review consists of twoparts. In the first, the main methods to control flow distribution were reviewed. Severaldifferent designs of inlet/outlet chambers were presented together with correspondingmodels used for optimization of flow distribution. In the second part, recent achievements inunderstanding of heat transfer in micro channels are presented

Bachok et al (2011) [39]has studied numerically a steady flow of an incompressible viscous fluiddue to a rotating disk in a nanofluid. The transformed boundary layer equations have beensolved numerically by a finite difference scheme, namely the Kellerbox method. Numericalresults for the flow and heat transfer characteristics were obtained for various values of thenanoparticle volume fraction and suction/injection parameter. Two models for the effective thermal conductivity of the nanofluid, namely the Maxwell–Garnett model and the Patelmodel, were considered. It was found that for the Patel model, the heat transfer rate at the surface increases for both suction and injection, whereas different behaviours were observed for the Maxwell–Garnett model.

Allen (2007) [40] had investigated fluid flow and heat transfer in microchannels experimentally and numerically. Fluid flow and heat transfer experiments were conducted on a copper microchannel heat exchanger with constant surface temperature. The experimentally obtained friction factor were found fairly well agreement with theoretical correlations and moreover the experimental Nusselt number results agreed with theory very well in the transition/turbulent regime, but the results show a higher Nusselt number in the laminarregime than predicted by theoretical correlations. Philips created a CFD model to simulate the fluid in the inlet plenum and the microchannels. The results from these simulations showedgood agreement with the experimental data in the transition/turbulent regime as well as with theoretical correlations for laminar and turbulent flow.

CHAPTER -3

COMPUTATIONAL FLUID DYNAMICS- THEORY AND MODEL EQUATIONS

Computational fluid dynamics (CFD) is that area of fluid mechanics which uses set of particular numerical algorithms and calculations to tackle and dissect issues which includesflow of fluid. The codes which are used for CFD analysis are well established and along these lines give a decent start to more intricate heat exchanger and fluid flow issues. Application of the CFD for the analysis of a fluid problem is done in thesesteps.

- 1. First of all, the mathematical equations which are used to describe the motion of fluid; are written in the form of partial differential equations. After that, these partial equations are discretized.
- 2. The area of interest in CFD analysis is then assigned as different domains. Now, the domain is divided intoseveral small parts known as grids or elements.
- 3. In the last, the specific boundary conditions are applied as per the problem for solving the equations.

The solution can be achieved directly or through iteration. Apart from this, a number of control parameters are used to specify convergenceand accuracy. All CFD codes consisof following:

- A pre-processor- To input the problem geometry, mesh generation and to set boundary conditions of particular problem.
- A flow solver-To solve the governing equations applied on fluid flow. A flow solver can use following methods:
 - (i) finite element method,
 - (ii) finite difference method;
 - (iii) finite volume method, and
 - (iv) spectral method

A post-processor- To give the output data and to show the results in graphical manner.

3.1 Mathematical formulation: Governing Equations

The governing equations include the equation of continuity, momentum equationand energy equation. The velocity vector is obtained using the continuity and momentum. The energy equation is utilized to gettemperature variationat various planes. The governing equations are written here in their general form.

3.1.1 Mass Conservation Equation

The continuity equation is shown below:

$$\frac{\partial \rho}{\partial t} + \nabla . (\rho \vec{\upsilon}) = S_m \tag{3.1}$$

Equation (3.1) is the general form of the mass conservation equation. This general form of continuity equation is valid for all kinds of fluid flow; whether it is compressible flow or incompressible. The S_m represents the additional masswhich is added to compensate any loss.

3.1.2 Momentum Conservation Equation

Conservation of momentum equation can be written as:

$$\frac{\partial}{\partial t}(\rho\vec{\upsilon}) + \nabla .(\rho\vec{\upsilon}\vec{\upsilon}) = -\nabla p + \nabla .(\overline{\vec{\tau}}) + \rho\vec{g} + \vec{F}$$
(3.2)

Where

- *p*-is the static pressure.
- $\overline{\overline{\tau}}$ -The stress tensor (described below), and
- $\rho \vec{g}$ and \vec{F} the gravitational body force and external body forces.

The stress tensor is given by

$$\overline{\overline{\tau}} = \mu \left[(\nabla \, \overline{\nu} + \nabla \, \overline{\nu}^{\,\mathrm{T}}) - \frac{2}{3} \nabla . \overline{\nu} I \right]$$
(3.3)

Where

- μ : The molecular viscosity,
- I: The unit tensor and
- The second term on the rightside is the result of volume enhancement.

3.1.3 Energy equation

Energy equation in fluent is used in the following form:

$$\frac{\partial}{\partial t}(\rho E) + \nabla . \left(\vec{\upsilon} \left(\rho E + p\right)\right) = \nabla . \left(\kappa_{eff} \nabla T - \sum_{j} h_{j} \overrightarrow{J_{j}} + \left(\overline{\overline{\tau}}_{eff} . \vec{\upsilon}\right)\right) + S_{h}$$
(3.4)

Where

- κ_{eff} is the effective conductivity
- J_j is the diffusion flux of species J and
- The initial three terms on the right-hand side of equation gives energy exchange because of conduction, species dissemination, and viscosity changes, separately. S_h incorporates the heat of chemical reaction etc.

3.2 Boundary Conditions

The governing equation of fluid flow may bring about an answer when the boundary conditions and the underlying conditions are indicated. By and large, the boundary conditions are appointed either as the numerical terms. In case of steady state fluid flow, three sorts of boundary conditions are used:

- I. Dirichlet boundary condition
- II. Neuman boundary condition and
- III. Mixed boundary condition

The general boundary condition which are observed in fluid flow are:

- (A) Solid Walls : They can be moving or stationary.
- (B) Inlets: Fluid entrance point.
- (C) Symmetry boundary: Fluid flow is symmetrical about any wall or plane.
- (D) Cyclic boundary: It is in pairs having identical values at some particular place.

(E) Pressure Boundary Conditions: Identification of pressure boundary condition at one or more than one boundaries is a very important and useful thing. Pressure boundaries are identified by restricted storage of fluid, operationalambience and pressures generated by any mechanical devices.

(F) Opening Boundary Conditions: Fluid may go out or can enter without any restriction.

(G) Free Surfaces and Interfaces:Surface tension comes in to play in case of free surfaces..

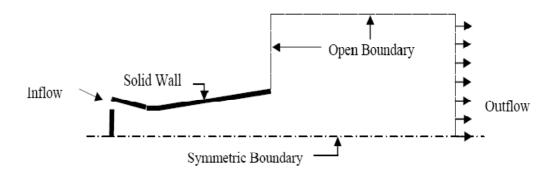


Fig.3.1 Various Boundary conditions

3.3 Techniques for Numerical Discretization

3.3.1 The Finite Difference Method

Taylor series expansion is used tofind out the derivatives of anyvariable. It is used as the differences between values of the different variable at various locations. 3.3.2 The Finite Element Method

3.3.2 The Finite Element Method

The fluid domain of interest is divided in to several elements. A simple function is assigned for every variable under each element. Then, change in variation is summarized to find flow field.

3.3.3 The Finite Volume Method

The finite volume method is currently the most used method in CFD. It is also called the Cell Centered (CC) Method. In FVM,the flowgoverning parameters are assigned at the center of the computational volume.

3.3.4 Spectral Methods

Fourier series is used to approximate the unknown values.

CHAPTER-4

MICROCHANNEL HEAT SINK-THEORY, MODEL EQUATIONS AND FABRICATION TECHNOLOGY

Microchannel heat sinks are composed of very small channels cut through a metal or semiconductor. They can also be considered as small fins that are placed extremely close to the heat dissipating element. These channels have very small hydraulic diameter (in microns' level) which increases film heat transfer coefficient h, to a very high level. This in turn increases the heat transfer rate which is a key requirement in today's high performing semiconductor devices.

4.1 Why Microchannel?

The heat transfer due to convection is given by:

 $Q = hA(T_{\text{solid}} - T_{\text{liquid}})$

Thus the heat transferred can be increased either by making

- ➢ Area "A"larger
- Heat transfer coefficient" h" larger or
- Increasing the temperature difference

The heat transfer coefficient h is given by:

$$h = NuK/D_h$$
 4.1

Where D_h is the hydraulic diameter of the channel and Nu is the Nusselt number characteristic for the flow. It is clear that for a fixed Nusselt number in a channel flow, heat transfer coefficient can be increased by reducing its hydraulic diameter; D_h .However the decrease in the diameter results in a very large increase of the pressure drop inside the channel. Thus in applications where the heat flux is large, microchannel heat sink helpsto maximize the convective heat transfer coefficient, and also decrease size and cost.

4.2 Microchannel Heat sink- Model Equations

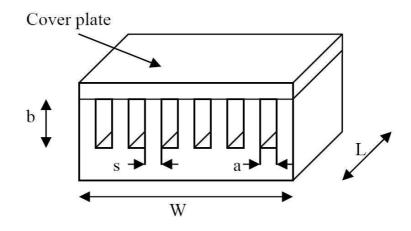


Fig. 4.1 Schematic representation of Microchannel heat sink

In the above schematic, width "a" and depth" b" are the main important sides of microchannel heatsink which plays an important role in heat transfer. The channel length "L"is decided on the basis of semiconductor chip dimension. The number of channels is governed by the width of channel "a". The gap between two channels is referred as wall thickness is shown here as "s".

The number of channels "n" can be calculated from:

$$n = W/(a+s) \tag{4.2}$$

The hydraulic diameter is derived from:

$$D_h = 4ab/2(a+b) \tag{4.3}$$

The channel aspect ratio is given by:

$$\alpha = b/a \tag{4.4}$$

4.2.1Heat transfer in microchannels

In classical analysis, Nusselt number is assumed to be constant when the flow is in fully developed laminar region. The Nusselt number in above case is fixed and it is dependent upon the channel shape and the heat transfer conditions at the wall from where heat load is applied. Table 4.1 shows the Nusselt numbers for generally utilized shapes with constant wall heat flux and constant wall temperature.

In 1978, Shah and London gave the following relation to a rectangular channel. The short side is designated by "a" and long side "b". Then channel aspect ratio is defined as; $\alpha_c = a/b$.

$$P_{o} = f \operatorname{Re} = 24(1-1.3553 \alpha_{c} + 1.9467 \alpha_{c}^{2} - 1.7012 \alpha_{c}^{3} + 0.9564 \alpha_{c}^{4} - 0.2537 \alpha_{c}^{5})$$
(4.5)
Po is Poiseuille number.

In case, the geometry of channel is rectangular, the Nusselt number is dependent on the channel aspect ratio $\alpha_c = a/b$, and the boundary conditions of wall of heat flux. Depending upon various wall conditions, three types of boundary conditions are specified andNusselt number in each case is described here.

1. Constant wall temperature, T-boundary condition:

$$Nu_{T} = 7.541(1 - 2.610\alpha_{c} + 4.970\alpha_{c}^{2} - 5.119\alpha_{c}^{3} + 2.702\alpha_{c}^{4} - 0.548\alpha_{c}^{5})$$
(4.6)

2. Constant circumferential wall temperature, uniform axial heat flux, H1 boundary condition:

$$Nu_{H1} = 8.235(1 - 2.0421\alpha_{c} + 3.0853\alpha_{c}^{2} - 2.4765\alpha_{c}^{3} + 1.0578\alpha_{c}^{4} - 0.1861\alpha_{c}^{5})$$
(4.7)

3. Constant wall heat flux, both circumferentially and axially:

 $Nu_{H2} = 8.235(1 - 10.6044\alpha_{c} + 61.1755\alpha_{c}^{2} - 155.1803\alpha_{c}^{3} + 176.9203\alpha_{c}^{4} - 72.9236\alpha_{c}^{5})$ (4.8)

Table 4.1 Nusselt No. For Various Geometries

Fanning friction factor and Nusselt number for fully developed laminar flow in ducts, derived from Kakac et al. (1987).

Duct shape			Nu _H	Nu_T	Po = f Re
\bigcirc	Circular		4.36	3.66	16
b	Flat channel		8.24	7.54	24
b	Rectangular, aspect ratio, $b/a =$	1 2 3 4 6 8 ∞	3.61 4.13 4.79 5.33 6.05 6.49 8.24	2.98 3.39 3.96 4.44 5.14 5.60 7.54	14.23 15.55 17.09 18.23 19.70 20.58 24.00
\bigcirc	Hexagon		4.00	3.34	15.05
θ	Isosceles Triangle, Apex angle $\theta =$	10° 30° 60° 90° 120°	2.45 2.91 3.11 2.98 2.68	1.61 2.26 2.47 2.34 2.00	12.47 13.07 13.33 13.15 12.74
	Ellipse, Major/Minor axis $a/b =$ \downarrow b \downarrow	1 2 4 8 16	4.36 4.56 4.88 5.09 5.18	3.66 3.74 3.79 3.72 3.65	16.00 16.82 18.24 19.15 19.54

 $Nu = hD_h/k$; $Re = \rho u_m D_h/\mu$; $Nu_H - Nu$ under a constant heat flux boundary condition, constant axial heat flux, and uniform circumferential temperature; $Nu_T - Nu$ under a constant wall temperature boundary condition; f - friction factor.

In actuality, every handy circumstance falls some place amidst these three conditions. This turns into a particularly critical issue on account of microchannels as a result of the trouble in recognizing a suitable condition.

4.3 Metallic Microchannel heatsink

Metallic microchannel heatsink is used to remove the heat generated by high heat flux generating semiconductor devices. The metallic microchannel heatsink is made from several thin sheets. All the metal sheet or laminates which are used for the fabrication purpose is precisely machined with tolerances of the order of approximately 10 μ m. Afterwards, these sheets are joined together at high temperature to form themicrochannels. Electrolytic or galvanic corrosion and erosion of the internal structure of microchannels are major concern. Deionized water is normally used in microchannel which is used to avoid the electrical connection between the water and the semiconductor device. This deionized wateris the main source of this metallic erosion.

Due to this erosion, the smallmetalparticles are dislodged which can block the microstructure. To minimize these effects, a chiller equipped capable of filtering particles below $20 \,\mu m$ is needed.

4.4 Fabrication of micro channels

Single crystal silicon, polycrystalline silicon and metals such as copper are used for the construction of micro channels.

Certain basic processes:

4.4.1 Photolithography: A photosensitive emulsion layer called photoresist, which are used to transfer a pattern through a mask to a semiconductor wafer. A mask is made from a transparent glass plate which is having chromium patterns overthem. A process called spin coating is used to deposit a layer of photoresist of the required thickness on silicon. After preparing a mask by the above process, channels can be produced through many processes.

4.4.2 Anisotropic Wet Etching

In this process, the channels are cut using chemical etchants such as Alkali hydroxides (NaOH, KOH, CsOH), ammonium hydroxide, and others like hydrazine and water.

Chemical Reaction:

Si + 2OH⁻ → Si(OH)₂²⁺ +4e⁻

$$4H_2O + 4e^- → 4OH^- + 2H_2$$

Si(OH)₂²⁺ +4OH⁻ → SiO2(OH)₂²⁻ + 2H₂O

With the use of KOH for anisotropic etching V shaped grooves can be achieved conveniently. Tapered walls in silicon can also be etched through this method.

By Using wafers of different orientation we can get different etch profiles and differently shaped channels. The depth of the channels is controlled by the etching time and the concentration of the etchant.

The channel is covered with a glass or silicon sheet which are joined through Anodic bonding. The dimensions of the channel produced are about 300 micrometers deep and 100 micrometers wide.

4.4.3 Anisotropic Dry Etching

This process allows us to etch high aspect ratio trenches in the silicon wafer. It does not depend on the crystalline orientation of the surface.

It is usually alternated with Chemical vapor deposition which is used to protect the etched surface, for e.g. SF_6 is deposited to prevent etching of the walls and the bottom etched to give a deeper channel.

4.4.4 DRIE and RIE (Reactive ion etching):

In DRIE, thin films of two different materials are used. One film as a structural material (commonly polysilicon) and another film is called sacrificial material (oxide). These thin films are deposited and dry etched in an order of sequence. In the last, the second layer which is sacrificial material is wet etched for the release the desired structure.

4.4.5 Fabrication of micro channels in copper

Copper is another material that is used to make heat sinks due to its high thermal conductivity and can also be used to make micro channels.

4.4.5.1 Laser Micromachining

Commonly used lasers are:

- 1) Excimer lasers with UV wavelength
- 2) Nd:YAG with infrared and visible and UV wavelength
- 3) CO_2 laser with deep infrared wavelength

In laser machining, very short duration laser pulses are used to remove material. The pulse duration, intensity of laser and optics are decided on the basis of thickness of the material to be removed. A mask is used to remove material from selective region. As, the laser beam can be focused to a very small size, quite complex and narrow dimensions can be achieved.

4.4.5.2 Focused Ion Beam Milling

In focused ion beam milling also, we can get the spot size as low as 10 nm or even less than that. A beam of energetic ion which is highly focused at the target cuts the particular site of interest.

4.4.5.3 Micro Electro Discharge Machining (Micro EDM)

In Micro EDM process, sparks are created between electrode (tool) and a workpiece toremove material from material. The spark generates local temperatures as high as 10000°C. This high temperature melts the metal and removes it from site.

CHAPTER-5

MODELING OF FLUID FLOW IN RECTANGULAR MICROCHANNEL

In this section, theCFD analysis of fluid flow and heat transfer in a rectangular microchannel is explained. These micro channels are fixed inside test module. The experimental setup was developed by (Qu and Mudawar,2002) which is shown in Fig. 5.1. The details of micro channel test set up are shown in Fig.5.2. (Qu and Mudawar, 2002). These micro channels are fabricated from oxygen free high conductivity copper. The top of heat sink is covered by polycarbonate sheet.

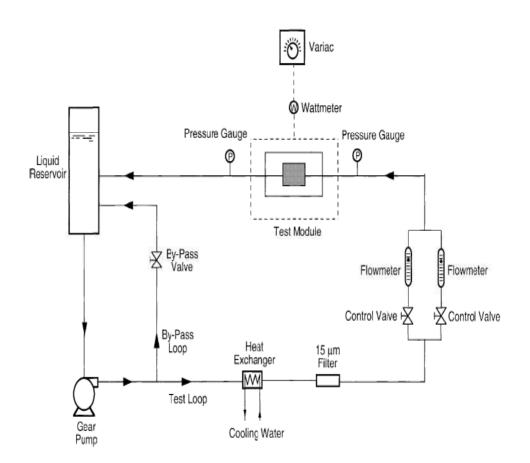


Figure 5.1 Experimental arrangement for testing of micro channel(*Qu and Mudawr;2002*)

5.1 Problem description

In this work, the simulation is carried out on the experimental set up which was used by Lee and Mudawar, (2002) . Fluid (deionized water) is forced to pass through the rectangular micro channels which are fixed in a test set up. In this work, total 21 microchannels are there. They all are rectangular in shape and parallel to each other. The sides of a single microchannel unitare as follows:

It is 231 μm inwidth, 713 μm in depth and 4.48 cm long. The hydraulic diameter of microchannel is found to be 349 μm . The inlet velocity is *u* (m/s) which depends upon flow rate.

The heat load at the bottom wall is provided by 12 cartridge heaters. These cartridge heaters are fixed inside the bottom wall of heat sink. The polycarbonate topcover plate of heat sink is exposed to convective conditions.

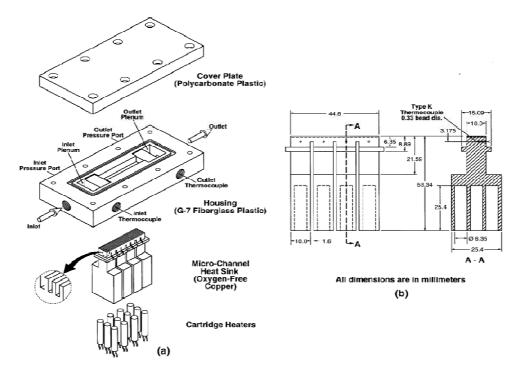


Figure 5.2 (a) Test module (b) Microchannel heat sink (Qu and Mudawr;2002)

The experiment was carried out at following conditions:

Demineralized water was used as the cooling media and two heat flux of $q''_{eff} = 100$ W/cm² and $q''_{eff} = 200$ W/cm² were applied at the bottom surface (Total area=4.48 cm²) of the heat sink. The Reynolds number range varied from 139 to 1672 in case of $q''_{eff} = 100$ W/cm², and 385 to 1289 in case of $q''_{eff} = 200$ W/cm² .Inlet temperature of fluid to the channel; $T_{in}=15^{\circ}$ C.

5.2 Detailed geometry of computational domain

In this analysis, half section of a single unit of micro channel istaken as computational domain due to symmetrical nature of microchannel. Figure 5.3 represents the single cell and its half sectioni.e. computationaldomain. Isometric view of computational domain (half section of unit cellof micro channel) is also shown in figure 5.4. The dimension of single micro channel and computational domain aregiven in Table 5.1 and Table 5.2 respectively.

Table 5.1 Dimensions of unit cell micro channel				
$W_{w}(\mu m)$	$W_{ch}(\mu m)$	H _{w1} (μ <i>m</i>)	$H_{ch}(\mu m)$	H _{w2} (μ <i>m</i>)
118	231	12700	713	5637

Table 5.1 Dimensions of unit cell micro channel

1 able 5.2 Dimensions of computational domain				
$W_w(\mu m)$	$W'_{ch}(\mu m)$	$H_{w1}(\mu m)$	$H_{ch}(\mu m)$	$H_{w2}(\mu m)$
	(in computational			
	domain)			
118	115.5	12700	713	5637

 Table 5.2 Dimensions of computational domain

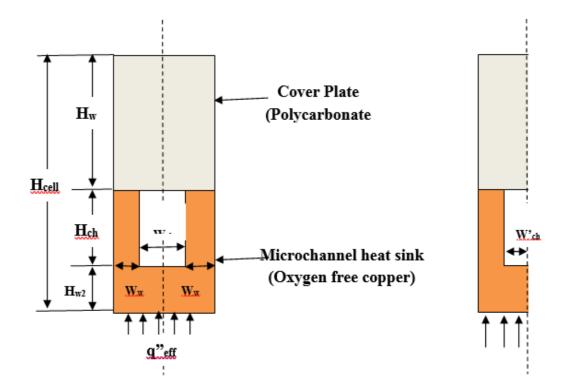


Figure 5.3 a) unit cell b) computational domain

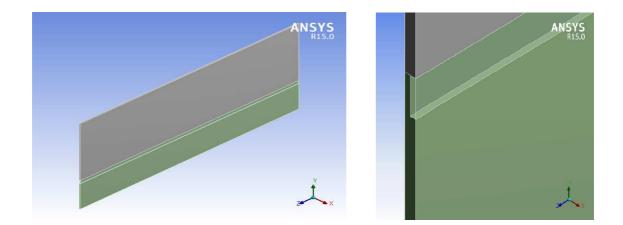


Figure 5.4 Isometric view of computational domain in ANSYS

The geometry of computational domain is prepared in solid works and heatsink bottom from outlet side is taken as origin (0,0). The length of geometry can be considered in negative –Z direction as shown in various graphs under section results and discussions. The dimension of the entire heat sink is: Width of Heat sink (X-direction) = 233.5 μm Height of Heat sink (Y- direction) = 19050 μm Length of Heat sink (Negative –Z Direction) = 44800 μm

5.3 Meshing of computational domain

Meshing is the most important step in any CFD analysis. The accuracy of result and time consumed during simulation work is greatly dependent upon the quality of mesh. In the current study, hexahedral mesh was used. Its detailed view is shown Fig. 5.5. Nodes and element were created using ANSYS meshing tool. The total number of mesh elements 1942320 and total number of nodes 2344509 were created. The total number of elements in fluid domain is1020088 as it is our prime area of interest.

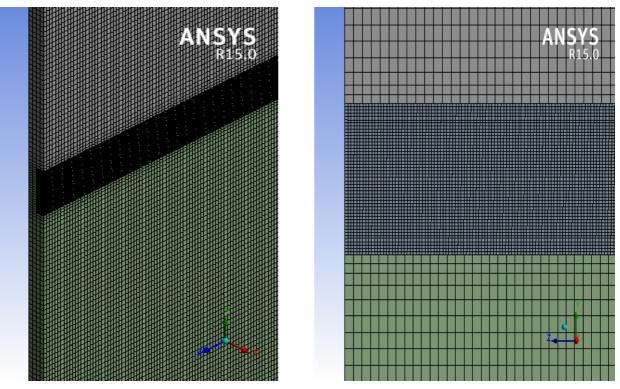


Figure 5.5 Isometric view of mesh structure in computational domain

5.4 Physical model

In this study, the Reynolds number $\text{Re}=\frac{\rho u D}{\mu}$, varies between 139-1672 which is much 2000. On the basis of the range of Reynolds number, the entire study is done with viscous laminar model keeping energy on.

5.5 Material properties

The properties of different material used in the present simulation work are given in table 5.3.

MATERIAL	THERMAL	SPECIFIC HEAT ,Cp
	CONDUCTIVITY, k (W/m.K)	(kJ/Kg.K)
WATEER	0.6	4.1855
COPPER	401	0.39
POLYCARBONATE	0.2	1.2

Table 5 2 Material Droportion

5.6 Governing Equations

The friction factor in microchannel is obtained from the pressure drop inside the channel

$$f_{=} \frac{\Delta P_{\rm ch}}{2Lu^2} \frac{D_h}{\rho_{\rm f}}$$
(5.1)

The heat flux for singleunit of microchannel is derived from equation (Qu and Mudawar 2007) [14]

$$q_{eff^{=}}^{\prime\prime} \frac{P_{w}}{NA_{bot}} (5.2)$$

N represents no. of microchannels. $A_{bot}=W_{Cell} \times L$ (area of bottom of single microchannel).

5.7 Boundary conditions

The hydraulic boundary conditions are assigned as follows:

The channel inlet is assigned with a uniform velocity i.e. $u=u_{in}$; v=0 and w=0.

Channel inner walls: No slip

Velocity inlet: Uniform velocity and constant inlet temperature (T_{in} = 15 0 C). The velocity is calculated from the mass flow rate.

Pressure outlet: Pressure was specified. The pressure was calculated from the pressure drop inside the channel.

Thermal boundary conditions are given as follows:

At single unit cell bottom, copper wall: Constant heat flux is applied.

At the top of single unit cell, polycarbonate wall: It is subjected to convective condition where film heat transfer coefficient, h=10 watt/m.K and T _{amb} = 25 ⁰C. All the other sink surfaces subjected toadiabatic conditions (heat flux is zero except bottom sink). The domain is designated"solid "in case of heat sink and "fluid" in case of channel. All boundary conditionsas per zone is shown in the table given below.

ZONE	ТҮРЕ	
Heat sink Inlet	Wall	
Heat sink Outlet	Wall	
Treat shik Outlet	vv all	
Heat sink Bottom	Heat flux	
Heat sink Top	Convection	
1		
Heat sink Left	Wall	
	vv an	
Heat sink Right	Wall	

 Table 5.4.
 Zone wise Boundary Condition

Channel Inlet	Velocity Inlet
Channel Outlet	Pressure Outlet
Channel bottom	Wall
Channel Left	Wall
Channe Right	Wall
Channel Top	Wall

5.8 Method of solution

In the present simulation work, solver uses a pressure velocity coupling method SIMPLE (Semi Implicit method for Pressure Linked equation) algorithm with 2^{nd} order upwind scheme. The convergence criteriawere given 10^{-7} for all parameters. The relaxation factors as per table 5.4 were used for calculations.

FACTORS	VALUE
PRESSURE	0.3
DENSITY	1
BODY FORCE	1
MOMENTUM	0.7
ENERGY	1

Table 5.5 Relaxation factor

CHAPTER-6

RESULTS AND DISCUSSIONS

The thermal behavior of the microchannel heat sink can be studied in terms of temperature distribution. The CFD analysis is carried out in two conditions at various key position of the microchannel heat sink. In first CFD analysis, the volume flow rate is 603 ml/min and the inlet velocity is 2.9056 m/sec for Reynolds number of 890. A heat flux of 100 W/cm^2 is applied at the bottom of heat sink. In second condition, the volume flow rate is 585 ml/min and the inlet velocity is 2.8189 m/sec for Reynolds number of 864. A heat flux of 200 W/cm² is applied at the bottom of heat sink. Thus the flow is laminar in both the cases.

In Fig. 6.1 and 6.11; temperature distribution along the length of bottom of heat sink is shown for Re= 890 atq_{eff} =100 W/cm² and Re=864 at q_{eff} =200 W/cm²respectively. It can be clearly observed that the temperature is almost linearly increasing from 320 K to 337.5 K and 352.5 K to 388 Krespectively in both the above cases while the inlet water temperature is fixed at 288 K. It is quite understandable that as the flow of water progresses, the temperature of water rises due to heat transfer from the bottom of heat sink to water. Due to this, the available temperature gradient reduces along the length of channel which in turn reduces the rate of heat transfer. That is why; temperature of bottom wall goes on increasing along the length of channel.

In Fig. 6.2 and 6.12; temperature distribution along the length of top of heat sink is shown at

Re= 890 at $q_{eff} = 100 \text{ W/cm}^2$ and Re=864 at $q_{eff} = 200 \text{ W/cm}^2$ respectively. It can be seen from the graph that the temperature is increasing from 300 K to 308 K and 308 K to 324 K at above conditions respectively. Such a low temperature rise owes to very low thermal conductivity of poly carbonate (K=0.2 W/m.K) cover which is subjected to natural convective conditions (h=10 W/m.K, T_{amb}= 298 K).

In Fig. 6.3 and 6.13; temperature distribution is shown along the length of bottom wall of microchannel at Re= 890 at q_{eff} =100 W/cm² and Re=864 at q_{eff} =200 W/cm²respectively. The graphs show the temperature variation along the complete bottom wall surface of microchannel. The temperature of water rises from 288 K at inlet to 325 K and 288 K to 362 K at the outlet of channel, in both the above conditions respectively. The water temperature rise along the flow direction is due to the constant heat flux applied at the bottom of heat sink. As the flow of water progresses, the temperature of water rises due to heat transfer from the bottom of heat sink to water. Due to this, the available temperature gradient keeps on reducing along the length of channel which in turn reduces the rate of heat transfer and raises the temperature of water towards the outlet of channel continuously.

In Fig. 6.4 and 6.14; temperature distribution is shown along the length of complete side wall of microchannel at Re= 890 at $q_{eff} = 100 \text{ W/cm}^2$ and Re=864 at $q_{eff} = 200 \text{ W/cm}^2$ respectively. The temperature of water rises from 288 K at inlet to 325 K and 288 K to 362 K at the outlet of channel, in both the above condition respectively. The reason for the temperature rise of water is same as in case of bottom wall of microchannel.

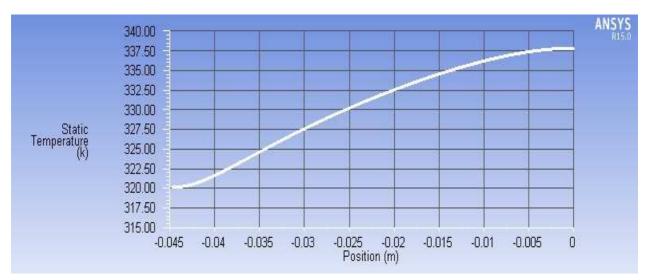
In Fig. 6.5 and 6.15; velocity contours are shown in complete fluid domain of microchannel at Re= 890 at $q_{eff} = 100 \text{ W/cm}^2$ and Re=864 at $q_{eff} = 200 \text{ W/cm}^2$ respectively. It can be clearly observed that the maximum velocity is at the center of the channel flow. In Fig. 6.6 and 6.16; velocity contours are shown in the area which is nearer to the inlet of microchannel at above conditions respectively. As the flow progresses, the growth of boundary layer can be clearly observed until the flow is fully hydrodynamically developed. It can also be observed from the Fig. 6.6 and 6.16; that the entrance length is becoming higher with the rise in Reynolds number. In Fig. 6.7 and 6.17; velocity contours are shown in the area which is nearer to the outlet of microchannel at above conditions respectively. It can be seen that flow is fully developed at the outlet of microchannel having maximum velocity at the center of microchannel.

In Fig.6.8 and 6.18; pressure contours is shown in the area which is nearer to the inlet of microchannel at Re= 890 at q_{eff} =100 W/cm^2 and Re=864 at q_{eff} =200 W/cm^2 respectively. It shows that the pressure keeps on decreasing linearly in the flow direction. This pressure drop is due to the friction which is directly proportional to pressure drop [equation-4.1]. In Fig. 6.9 and 6.19; pressure contours is shown in the area which is nearer to the outlet of microchannel at above conditions respectively. The increase in pressure drop, with increase in Reynolds number is also shown in Fig. 6.21 (both, experimental and numerical). Fig. 6.21 shows good similarity between the experimental and computed pressure drops. For a fluid with constant properties flowing through a rectangular channel, one would expect a linear relationship between pressure drop and Reynolds number. There are several reasons for the slope change in the pressure drop characteristics in Fig.6.21. First, forconstant power input and water inlet temperature, the outlet water temperature should decrease with increasingReynolds number as shown in Fig. 6.22. This in turn increases water viscosity, resulting in a larger pressure drop. Second, the inlet and outlet pressure losses are proportional to the square of velocity. Therefore, the increment in Reynolds number generates a greater effect in the inlet and outlet pressure losses.

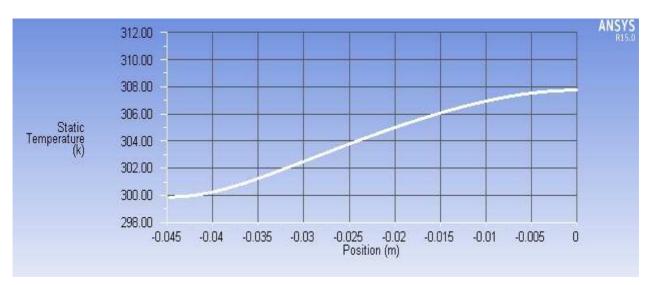
Fig. 6.22 gives the comparison between the experimental values of rise in temperature between the channel inlet and outlet, and theoretical values obtained from the energy balance

$$\rho_{\rm f} V c_{\rm p,f} (T_{\rm out} - T_{\rm in}) = P_{\rm W}. \tag{6.1}$$

In Fig. 6.10 and 6.20; the contours of temperature variation in complete heat sink at middle plane is shown for Re= 890 at $q_{eff} = 100 \text{ W/cm}^2$ and Re=864 at $q_{eff} = 200 \text{ W/cm}^2$ respectively. It shows that the highest temperature is encountered in the bottom wall of heat sink below the channel outlet and lowest temperature is obtained immediately below the channel inlet.

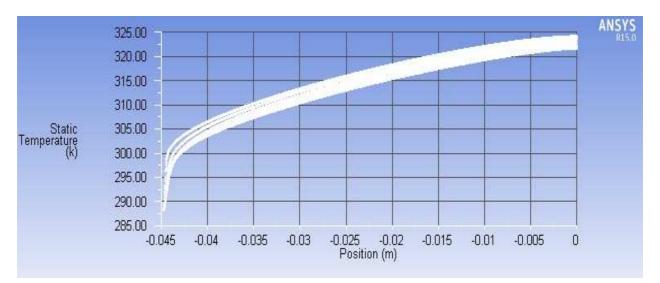


*Figure 6.1 Temperature distribution at bottom wall of Heat sink at qeff =100 W/cm2 and Re of 890

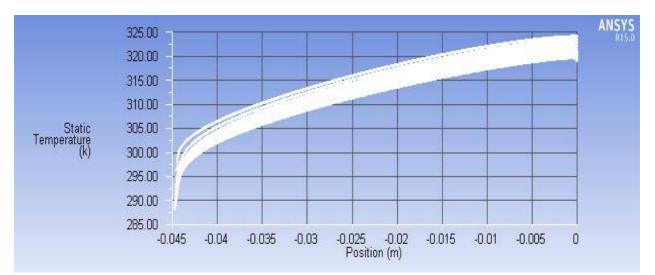


*Figure 6.2 Temperature distribution at Top wall of Heat sink at qeff = 100 W/cm2 and Re of 890

*The graph is started from negative values due to the reason that outlet of heat sink is assigned as origin i.e. zero point. The length of heat sink is 0.0448 m so graph starts from negative sign (-0.045 m)



*Figure 6.3 Temperature distribution at Channel bottom wall of Heat sink at qeff =100 W/cm2 and Re of 890



*Figure 6.4 Temperature distribution at Channel side wall of Heat sink at qeff =100 W/cm2 and Re of 890

*The graph is started from negative values due to the reason that outlet of heat sink is assigned as origin i.e. zero point. The length of heat sink is 0.0448 m so graph starts from negative sign (-0.045 m)

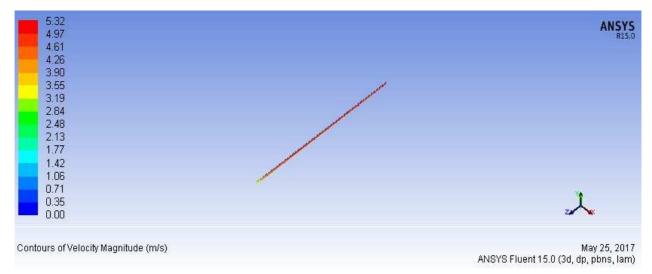


Figure 6.5Velocity contours in complete fluid domain at qeff = 100 W/cm2 and Re of 890

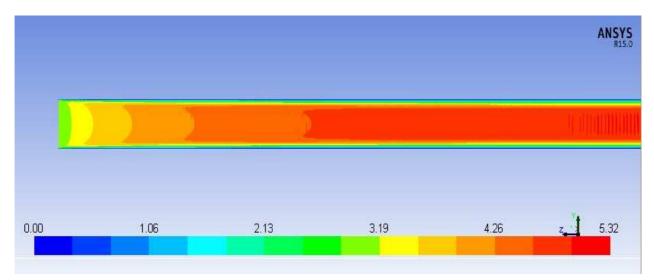


Figure 6.6 Velocity contours nearer to inlet at qeff =100 W/cm2 and Re of 890

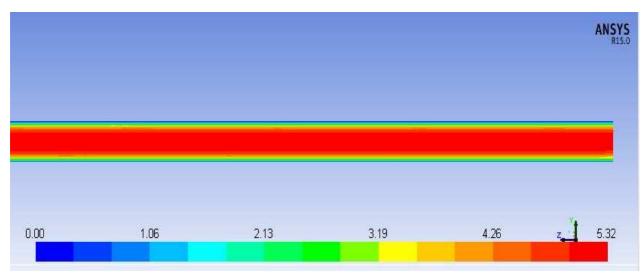


Figure 6.7 Velocity contours nearer to outlet at qeff =100 W/cm2 and Re of 890



Figure 6.8 Pressure contours nearer to inlet at qeff = 100 W/cm2 and Re of 890

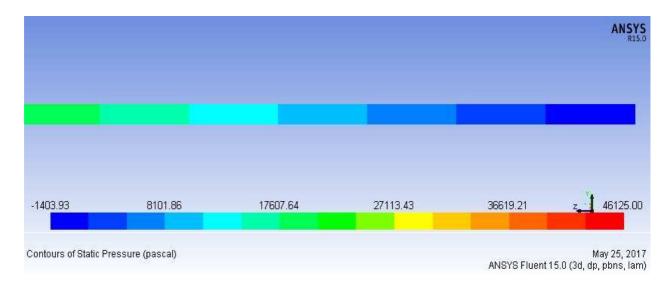


Figure 6.9 Pressure contours nearer to outlet at qeff =100 W/cm2 and Re of 890

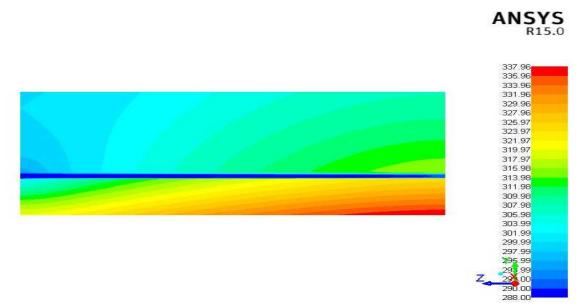
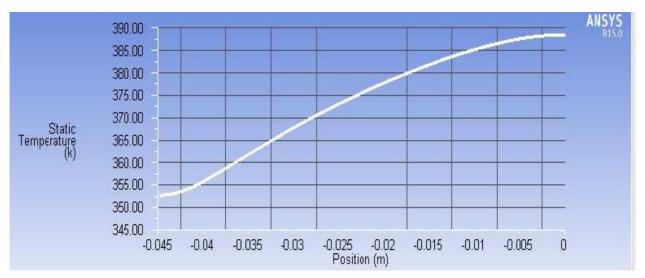
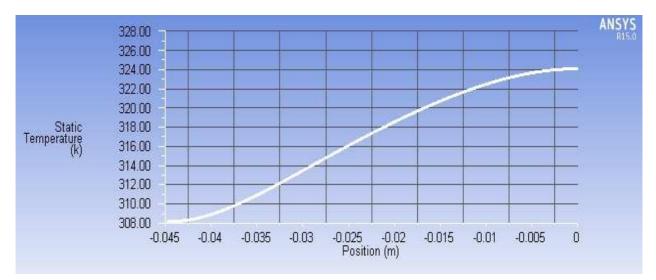


Figure 6.10Temperature contours of complete heat sink at symmetry plane at qeff =100 W/cm2 and Re of 890

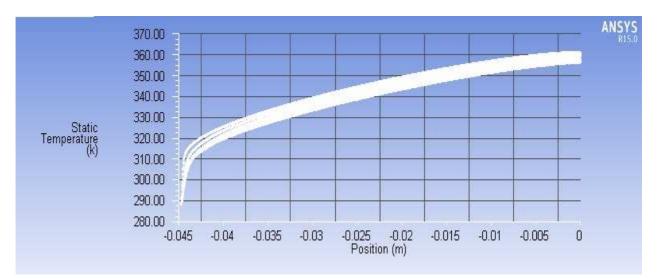


*Figure 6.11 Temperature distributions at bottom wall of Heat sink at qeff =200 W/cm2 and Re of 864

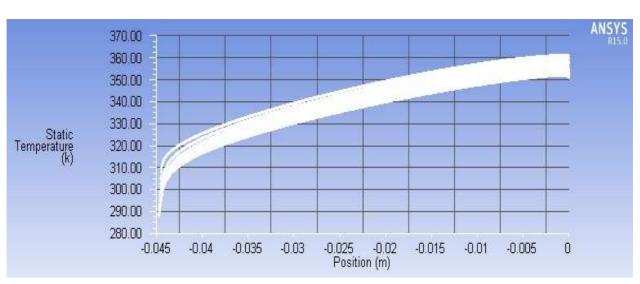


*Figure 6.12 Temperature distributions at top wall of Heat sink at qeff = 200 W/cm2 and Re of 864

*The graph is started from negative values due to the reason that outlet of heat sink is assigned as origin i.e. zero point. The length of heat sink is 0.0448 m so graph starts from negative sign (-0.045 m)



*Figure 6.13 Temperature distribution at Channel bottom wall of Heat sink at qeff =200 W/cm2 and Re of 864



*Figure 6.14 Temperature distribution at Channel side wall of Heat sink at qeff =200 W/cm2 and Re of 864

*The graph is started from negative values due to the reason that outlet of heat sink is assigned as origin i.e. zero point. The length of heat sink is 0.0448 m so graph starts from negative sign (-0.045 m)

ZZ

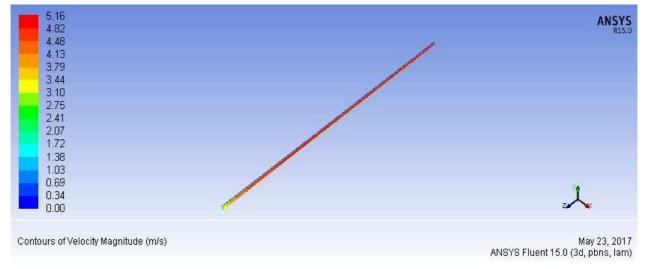


Figure 6.15 Velocity contours in entire fluid domain at qeff = 200 W/cm2 and Re of 864

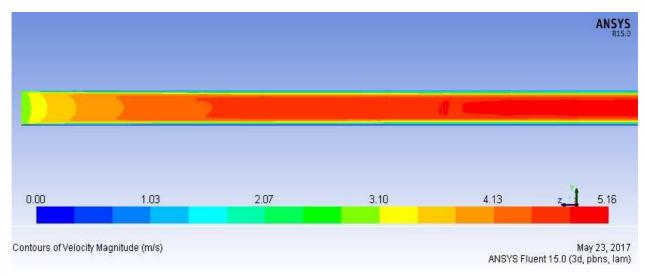


Figure 6.16 Velocity contours nearer to inlet at qeff =200 W/cm2 and Re of 864

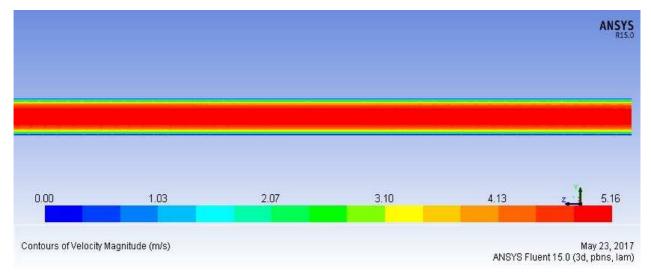


Figure 6.17Velocity contours nearer to inlet at qeff = 200 W/cm2 and Re of 864

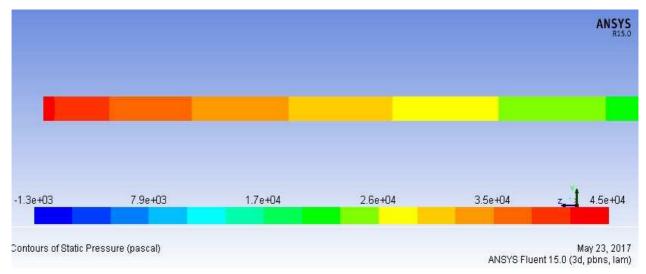


Figure 6.18 Pressure contours nearer to inlet at qeff = 200 W/cm2 and Re of 864

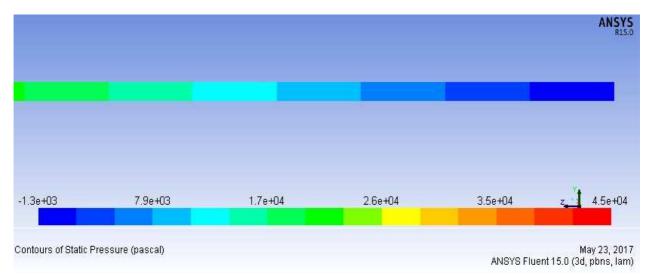


Figure 6.19Pressure contours nearer to inlet at qeff = 200 W/cm2 and Re of 864

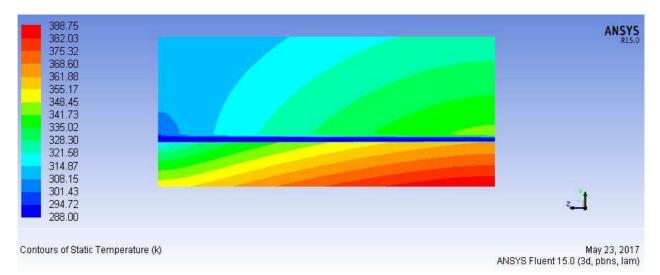


Figure 6.20 Temperature contours of complete heat sink at symmetry plane at qeff =200 W/cm2 and Re of 864

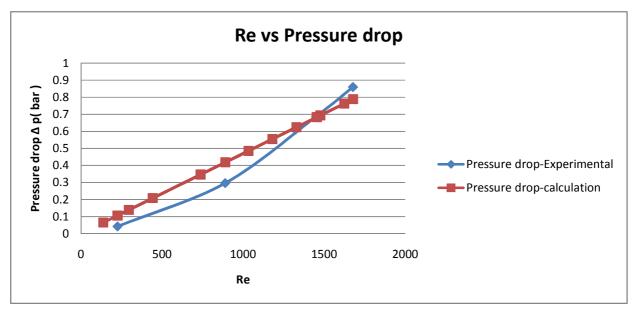


Figure 6.21Graph between Pressure drop and Reynolds Number

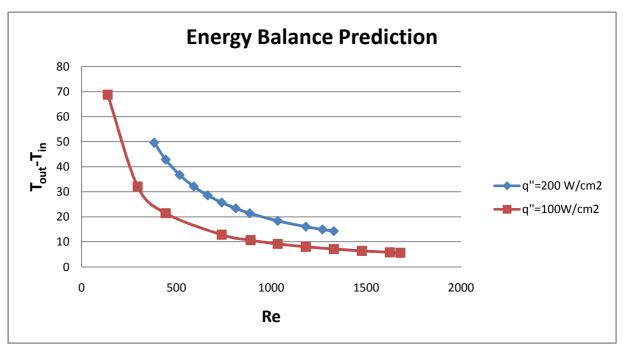


Figure 6.22 energy balance predictions for water temperature rise from heat sink inlet to outlet: (a) qeff=100 W/cm2, (b) q eff=200 W/cm2.

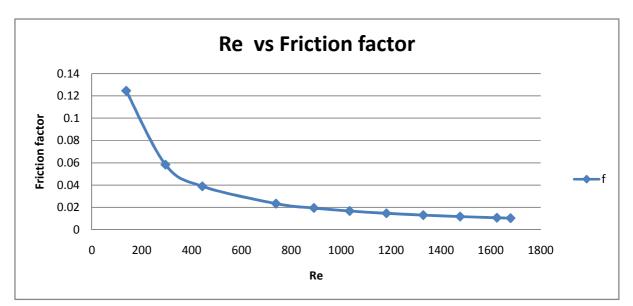


Figure 6.23Graph between friction factor and Reynolds Number

CHAPTER -7

CONCLUSIONS

In this study, the hydrodynamic and heat exchange analysis f rectangular microchannel in a test rig was studied. A steady state condition and laminar flow conditions were simulated by ANSYS Fluent 15.0 for the CFD analysis. Based on the above analysis; these conclusions can be drawn:

- The computated variation in temperature along heat sink walls and pressure drop inside channel can quite accuratelypredict the experimental results.
- A good agreement was obtained between the experimental data and results from CFD analysis for the temperature distribution within the heat sink and channel walls. Wall temperature increases in almost linear fashion from the entry of microchannel tothe exit of microchannel.
- Temperature contours, pressure contours and velocity contours successfully show the hydrodynamic and thermal nature of the heat sink.
- Higher Reynolds numbers are beneficial at reducing both the water outlet temperature and the temperatures within the heat sink, at the expense of greater pressure drop.
- The highest temperature is encountered in the bottom wall of heat sink below the channel outlet and lowest temperature is obtained immediately below the channel inlet.

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